

## Amendments to the Abstract

**Please amend the original abstract (page 27) as follows.**

### ABSTRACT

~~The present invention provides a~~A substrate cleaning apparatus~~which~~ allows an end face and/or a bevel face of a substrate to be scrub-cleaned in a simple and effective manner. The apparatus~~comprises~~has a plurality of rotatable substrate rotating rollers~~12 and 14~~ for gripping~~the~~a periphery of~~a~~the substrate and rotating the substrate, a cleaning roller~~48~~ capable of rotating and having a cleaning member~~52~~ which is to be brought into contact with~~an~~the end face and/or~~a~~the bevel face of the substrate so as to apply scrub-cleaning to the end face and/or the bevel face, and a power transmission mechanism~~64~~ for transmitting a rotating force of the substrate rotating roller~~14~~ to the cleaning roller~~48~~ so as to rotate the cleaning roller~~48~~.